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G. Stanley

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): MORIOKA, et al

Serial No.: 09/805,188

Filed: March 14, 2001

For: METHOD AND APPARATUS FOR ANALYZING THE STATE OF
GENERATION OF FOREIGN PARTICLES IN
SEMICONDUCTOR FABRICATION PROCESS

Group: 2877

Examiner: T. Nguyen

AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

January 15, 2002

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application in response to the Office Action dated November 15, 2001.

IN THE SPECIFICATION:

Page 1, please amend the paragraph beginning at line 5 as follows:

Cross-Reference to Related Applications

This application is a continuation application of U.S. application Serial No. 08/535,577, filed September 28, 1995, which is a continuation application of U.S. application Serial